

Campus in Garching



Research at the Physics Department of TUM

condensed matter physics / materials physics:

semiconductors magnetic materials superconductors polymers granular materials surface and interface physics

nuclear- and particle physics:

astro-particle physics physics of hadrons elementary particle physics neutron physics nuclear methods in interdisciplinary research

technical physics:

energy science medical physics opto- and nanoelectronics nanotechnology

biophysics:

biomaterials biosensors biological functions molecular machines

The Walter Schottky Institute (WSI)



research subjects

- materials technology and nanostructuring:
 - epitaxy, self-assembly, cleaved edge overgrowth, e-beam writing, laser processing,
- basic physics:
 - high mobility 2DEG's, magneto-transport
 - Quantum-Hall-Effect, Fractional Quantum Hall-Effect
 - quantum wires and dots
 - spin resonance
 - defect physics
 - uv-, visible-, and ir-spectroscopy
- developments for novel applications:
 - semiconductor lasers
 - quantum devices
 - spintronics
 - quantum information technology
 - photovoltaics
 - biosensors

Nanotechnology: ... quo vadis? Martin Stutzmann



WALTER SCHOTTKY INSTITUT TECHNISCHE UNIVERSITÄT MÜNCHEN

There's Plenty of Room at the Bottom

An Invitation to Enter a New Field of Physics



by Richard P. Feynman

This transcript of the classic talk that Richard Feynman gave on December 29th 1959 at the annual meeting of the <u>American Physical</u> <u>Society</u> at the <u>California Institute of Technology (Caltech)</u> was first published in the February 1960 issue of Caltech's <u>Engineering and</u> <u>Science</u>, which owns the copyright. It has been made available on the web at <u>http://www.zyvex.com/nanotech/feynman.html</u> with their kind permission. ... I would like to describe a field, in which little has been done, but in which an enormous amount can be done in principle...

...What I want to talk about is the problem of manipulating and controlling things on a small scale...

...In the year 2000, when they look back at this age, they will wonder why it was not until the year 1960 that anybody began seriously to move in this direction...

...The biological example of writing information on a small scale has inspired me to think of something that should be possible... Consider the possibility that we too can make a thing very small which does what we want---that we can manufacture an object that maneuvers at that level! ...

...There may even be an economic point to this business of making things very small...

...I want to build a billion tiny factories, models of each other, which are manufacturing simultaneously, drilling holes, stamping parts, and so on...

...We can use, not just circuits, but some system involving the quantized energy levels, or the interactions of quantized spins, etc...

...But it is interesting that it would be, in principle, possible (I think) for a physicist to synthesize any chemical substance that the chemist writes down. Give the orders and the physicist synthesizes it...

2006: "Nano" is everywhere…





Entwicklungsstand und Anwendungsfelder der Nanotechnologie

The economical side...

Aussagen zum weltweiten Marktvolum en der Nanotechnologie (in Mrd. €) aus unterschiedlich en Studien (Quelle: Deutsche Bank, Microtechnology Innovation Team)



Nano-Germany...



But also some criticism...(even with Nobel-Prize!)

Nano-whatever: Do we really know where we are heading?

Herbert Kroemer

ECE Department and Materials Department, University of California, Santa Barbara, CA 93106, USA.

...My skepticism pertains to the unbelievable hype that has arisen, during the last decade, about the "nano-whatever" field, a hype that exceeds anything I have encountered during my fifty years in solid-state physics and technology... Much of the hype is being generated by outsiders, not actually involved in these three areas, and basically clueless about how the process from science and technology actually works, but simply wishing to profit from the development....

...What is *not* acceptable—and what we must refrain from doing—is an attempt to justify the research by promising credibility-stretching mythical improvements in *existing* applications...

The challenges of Nanotechnology:

- Materials preparation and subsequent nanostructuring (,,top down")
- Controlled synthesis (,,bottom up")
- Growth by self-assembly (,,let's see what we have got on the average")
- Suitable analytical methods (,,look what we really have got")
- Controlled nano-assembly (,, really know what you will get")

The Prophet of "top down" Microelectronics: Gordon Moore (1960)

The experts look ahead

Cramming more components onto integrated circuits

With unit cost falling as the number of components per circuit rises, by 1975 economics may dictate squeezing as many as 65,000 components on a single silicon chip

By Gordon E. Moore

Director, Research and Development Laboratories, Fairchild Semiconductor division of Fairchild Camera and Instrument Corp.

The author



Dr. Gordon E. Moore is one of the new breed of electronic engineers, schooled in the physical sciences rather than in electronics. He earned a B.S. degree in chemistry from the University of California and a Ph.D degree in physical chemistry from the California Institute of Technology. He was one of the founders of Fairchild Semiconductor and has been director of the research and development laboratories since 1959. The future of integrated electronics is the future of electronics itself. The advantages of integration will bring about a proliferation of electronics, pushing this science into many new areas.

Integrated circuits will lead to such wonders as home computers—or at least terminals connected to a central computer—automatic controls for automobiles, and personal portable communications equipment. The electronic wristwatch needs only a display to be feasible today.

But the biggest potential lies in the production of large systems. In telephone communications, integrated circuits in digital filters will separate channels on multiplex equipment. Integrated circuits will also switch telephone circuits and perform data processing.

Computers will be more powerful, and will be organized in completely different ways. For example, memories built of integrated electronics may



Moore's Vision:



Semiconductor Nanoelectronics in 2006

3D-Elektronikaufbau Quelle:IBM



- Lateral dimensions approaching < 50 nm
- Control of layer thicknesses to less than a monolayer
- Process yields exceeding 95 %
- Complex 1D-, 2D-, und 3Dstructures produced reliably
- Photolithography remains the most efficient approach for parallel processing of complex nanostructures

Material Growth by MBE: atomic control of layer sequences



Halbleiter - Nano-Objekte (I)



- Herstellung von 2 D Quantenfilmen und Quantentöpfen durch atomar genaue Deposition unterschiedlicher Materialien
- Beherrscht seit etwa 30 Jahren (Epitaxie)
- Grundlage der modernen
 Optoelektronik (Leuchtdioden, Halbleiterlaser, Sensorik, Daten-Transfer)

Halbleiter - Nano-Objekte (II)





• Die Größenordnung aktueller Bauelemente der Silizium "Mikro"-Elektronik ist bereits in der eindimensionalen Nanowelt angekommen!

• Die Herstellung solch kleiner Strukturen wird zunehmend schwieriger und erfordert immense Investitionen.

• Das Verständnis auf atomarer Ebene wird unerläßlich!

The "Moore-Curve": the end of "conventional" semiconductor technology is coming closer ("it just happens…")!



Lithography at the 65 nm node



Table 77a Lithography Technology Requirements—Near-term UPDATED

ITRS: International Technology Roadmap for Semiconductors

	14010 / / 4							
	Year of Production	2003	2004	2005	2006	2007	2008	2009
	Technology Node		hp90			hp65		
	DRAM							
	DRAM 1/2 Pitch (nm)	100	90	80	70	65	57	50
	Contact in resist (nm)	130	110	100	90	80	70	60
	Contact after etch (nm)	115	100	90	80	70	65	55
WAS	Overlay	35	32	28	25	23	21	19
IS	Overlay [A]	35	32	28	25	23	21	19
	CD control (3 sigma) (nm)	12.2	11	9.8	8.6	8	7	6.1
	MPU							
	MPU/ASCI Metal 1 (M1) ½ pitch (nm)	120	107	95	85	76	67	60
	MPU ½ Pitch (nm) (uncontacted gate)	107	90	80	70	65	57	50
WAS	MPU gate in resist (nm)	65	53	45	40	35	32	28
IS	MPU gate in resist (nm)	65	♦ 53	45	40	35	32	28
WAS	MPU gate length after etch (nm)	45	37	32	28	25	22	20
	Contact in resist (nm)	130	122	100	90	80	75	60
	Contact after etch (nm)	120	107	95	85	76	67	60
	Gate CD control (3 sigma) (nm)	♦ 4.0	3.3	2.9	2.5	2.2	2	1.8
IS	Gate CD control (3 sigma) (nm)	♦ 4.0	• 3.3	2.9	2.5	2.2	2	1.8
WAS	ASIC/LP							
	ASIC ½ Pitch (nm) (uncontacted gate)	107	90	80	70	65	57	50
	ASIC/LP gate in resist (nm)	90	75	65	53	45	40	36
	ASIC/LP gate length after etch (nm)	65	53	45	37	32	28	25
IS		And in case of the local division of the loc	Statistics of the local division of the loca	And in the second s	the second s			25
10	ASIC/LP gate length after etch (nm)	65	53	45	37	32	28	20
	ASIC/LP gate length after etch (nm)	65 130		45 100	37 90	32 80	28	-
	Contact in resist (nm)	130	122	Commences of the local division of the local		-	Concession of the local division of the loca	60
	Contact in resist (nm) Contact after etch (nm)	130 120	122 107	100	90	80	75	60 60
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm)	130	122	100 95	90 85	80 76	75 67	60 60
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²)	130 120 5.8	122 107 4.7	100 95 4	90 85 3.3	80 76	75 67	60 60 2.2
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction	130 120 5.8 485	122 107 4.7 383	100 95	90 85 3.3 419	80 76 2.9	75 67 2.5	60 60 2.2 35
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction DRAM, production	130 120 5.8	122 107 4.7	100 95 4 568	90 85 3.3	80 76 2.9 662	75 67 2.5 449	60 60 2.2 35(104
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction DRAM, production MPU, high volume at introduction	130 120 5.8 485 139	122 107 4.7 383 110	100 95 4 568 82	90 85 3.3 419 122	80 76 2.9 662 97	75 67 2.5 449 131	60 60 2.2 350 104 280
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction DRAM, production MPU, high volume at introduction MPU, high volume at production	130 120 5.8 485 139 280 140	122 107 4.7 383 110 280	100 95 4 568 82 280	90 85 3.3 419 122 280	80 76 2.9 662 97 280	75 67 2.5 449 131 280	60 60 2.2 350 104 280 140
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction DRAM, production MPU, high volume at introduction MPU, high volume at production MPU, high performance	130 120 5.8 485 139 280 140 310	122 107 4.7 383 110 280 140	100 95 4 568 82 280 140	90 85 3.3 419 122 280 140	80 76 2.9 662 97 280 140	75 67 2.5 449 131 280 140	60 60 2.2 350 104 280 140 310
	Contact in resist (nm) Contact after etch (nm) CD control (3 sigma) (nm) Chip size (mm ²) DRAM, introduction DRAM, production MPU, high volume at introduction MPU, high volume at production	130 120 5.8 485 139 280 140	122 107 4.7 383 110 280 140 310	100 95 4 568 82 280 140 310	90 85 3.3 419 122 280 140 310	80 76 2.9 662 97 280 140 310	75 67 2.5 449 131 280 140 310	2356 60 2.2 356 104 280 140 310 704 704

Manufacturable solutions exist, and are being optimized Manufacturable solutions are known



Interim solutions are known Manufacturable solutions are NOT known



10 billion components 8 inch diameter



6 billion people 8000 mile diameter

Light path in an EUV exposure tool





EUVL-Stepperanlage für die Chipherstellung Quelle: Carl Zeiss SMT AG Simulation of Nano-Transistors: understanding the electronic and device properties on an atomic level. Single atom defects can have a big influence on nanostructure devices.



Challenges of the ,,top-down" technology

• Going nano requires novel materials, technologies, and measurement tools.

• The physical limits of silicon-based nanotechnology are within reach (2015?).

• Only very few companies will be able to make the financial investment necessary for the next step.

Self-organized semiconductor nanostructures: the solution?



Self-organized growth of nanowires und nanodots:

Artificial atoms and wires



Vertical CNT Transistor





Courtesy of Infineon Technologies

IBM unveils world's smallest transistor

09:05 Monday 9th December 2002 John G. Spooner, CNET News.com



State of the art...



... but makes a great movie!



Single quantum dot devices

Photoluminescence and photocurrent spectroscopy on the same QD as function of an external voltage V_{ext}



Single electron charging from the n⁺-GaAs back-contact Coulomb-charging Energy: $C_{QD} \sim 5 \times 10^{-18} F \rightarrow E_c \sim 20 \text{ meV}$

Advanced simulation tools





Old Materials with New Functionality



Biocompatible electronic devices with structure sizes in the 10 nm range...

Forms of Diamond grown by CVD



Single crystal:

1 inch substrates by 2006 (?)



100.0 лм 50.0 лм

Polycrystalline:

On 6 inch substrates (Si, Ir) commercially available Nano- or ultrananocrystalline: available as thin film on everything...

The "bottom up" approach



Organic Molecules

Organic Material for electronics

- Electroluminescent devices
- Organic Transistors
- Organic Lasers
- Organic Solar Cells

Conventional devices with organic semiconductors

Molecular Electronics

- Diodes
- Transistors
- Memories

New devices with nanosize dimension

Self-assembled monolayers

porphyrin molecules can be functionalized with thiol-derivatized chains in order to be covalently bounded onto gold surface



Molecular Digital Electronics





Data storage with atomic resolution?



Scanning Probe Systems as the central tool for nanotechnology and nanoassembly



The ultimate challenge: efficient and accurate nanoassembly

